	Application No.	Applicant(s)	
Notice of Allowability	10/017,415	LEE ET AL.	
	Examiner	Art Unit	
	Zeinab E. EL-Arini	1746	
The MAILING DATE of this communication appeal All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIOF the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate comm IGHTS. This application is a and MPEP 1308.	n this application. If not incl unication will be mailed in d	uded ue course. THIS
2. The allowed claim(s) is/are 1-18 and 26-27 (renumbered 1			
 3. ☐ The drawings filed on 18 December 2001 are accepted by 			
 4. ☐ Acknowledgment is made of a claim for foreign priority ur a) ☐ All b) ☐ Some* c) ☐ None of the: 1. ☐ Certified copies of the priority documents have 2. ☐ Certified copies of the priority documents have 3. ☐ Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 	e been received. e been received in Application	on No	ication from the
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file IENT of this application.	e a reply complying with the	requirements
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give			r NOTICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") mus	st.be submitted.		
(a) 🔲 including changes required by the Notice of Draftspers	on's Patent Drawing Review	w (PTO-948) attached	
1) 🗌 hereto or 2) 🗍 to Paper No./Mail Date			
(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date	s Amendment / Comment o	r in the Office action of	
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in t	.84(c)) should be written on t he header according to 37 CF	he drawings in the front (not R 1.121(d).	the back) of
7. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT			I. Note the
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☑ Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ⊠ Interview S	formal Patent Application (Fundamental Patent Application (Fun	PTO-152)
Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date		/Mail Date <u>101204</u> . Amendment/Comment	
Examiner's Comment Regarding Requirement for Deposit of Biological Material	9. 🗌 Other	Statement of Reasons for A	Allowance
	AB EL-ARINI RY EXAMINER		

Application/Control Number: 10/017,415

Art Unit: 1746

DETAILED ACTION

EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Adam Volentine on 10/08/04.

The application has been amended as follows:

The title has been changed to read "A single type of semiconductor wafer cleaning apparatus".

In claim 1, line 16, claim 11, line 17, "diffusion" has been changed to read "dissolving".

In claims 26, 27, lines 4 and 5 have been deleted. In claim 26, line 10, and in claim 27, line 11, before "and", --------"de-ionized water supply means for supplying de-ionized water onto a wafer at a location outside said chamber when the wafer is mounted to the chuck, to thereby provide a layer of de-ionized water on the wafer;"----has been inserted.

Art Unit: 1746

- 2. Claims 1-18 and 26-27 are allowed.
- 3. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Franz (JP 11-054472) discloses device for treating wafer like object, particularly silicon wafer. Matsukawa et al. (5,964,954) disclose double-sided substrate cleaning apparatus and cleaning method using the same. JP'472 or Matsukawa et al. do not disclose a single type of semiconductor wafer cleaning apparatus comprising de-ionized water supply means for supplying de-ionized water onto a wafer at a location outside a chamber when the wafer is mounted to the chuck, to thereby provide a layer of de-ionized water on the wafer as claimed.
- 4. The following is an examiner's statement of reasons for allowance:
 The prior art of record failed to teach a single type of semiconductor wafer cleaning apparatus comprising de-ionized water supply means for supplying de-ionized water onto a wafer at a location outside a gas guard defining a chamber when the wafer is mounted to a chuck, to thereby provide a layer of de-ionized water on the wafer as claimed.

Application/Control Number: 10/017,415

Art Unit: 1746

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Zeinab E. EL-Arini whose telephone number is (571) 272-1301. The examiner can normally be reached on Monday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Michael Barr can be reached on (571) 272-1414. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Application/Control Number: 10/017,415

Art Unit: 1746

Page 5

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Zeinab E. EL-Arini Primary Examiner Art Unit 1746

ZEE

010/12/04